

## **LISTING OF THE CLAIMS**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**1. - 40. (Canceled)**

**41. (New)** A method for processing a substrate to remove organic matter from said substrate by utilizing a substrate processing apparatus, comprising:

using a process chamber composed of a light-blocking material, wherein a viewing window for viewing an interior of said process chamber is provided on the wall of said process chamber;

using a holding element to hold said substrate in said process chamber;

using a removal liquid supply element to supply a removal liquid to said substrate held by said holding element;

using an indexer section including an indexer mechanism to directly load and unload said substrate into and out of a carrier set at a predetermined position;

using a first light-blocking section, provided in an opening that is disposed in said process chamber and which allows for the passage of said substrate, for blocking light passing through said opening into said process chamber; and

using a plurality of second light-blocking sections that are disposed in a plurality of locations along a transport path for said substrate that extends from said indexer section to said process chamber, respectively, and said light-blocking sections being respectively capable of blocking light passing through said transport path into said process chamber; and

preventing opening of said viewing window at least during a period of time when said substrate is being processed with said removal liquid.

**42. (New)** The method for processing a substrate according to claim 41, further comprising the steps of:

monitoring whether said viewing window is opened or closed;

illuminating the inside of said process chamber with an illumination element provided in the inside of said process chamber when the opening of said viewing window is detected in said step; and

stopping illumination with said illumination element when the closing of said viewing window is detected in said monitoring step.

**43. (New)** The method for processing a substrate according to claim 42, further comprising the step of:

prohibiting the supply of said removal liquid at least during a period of time when said viewing window is opened.